

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT:	M. Hatanaka et al.	CONF. NO.:	8004
U.S. SERIAL NO.:	09/471,829	EXAMINER:	P. Connolly
FILED:	December 23, 1999	GROUP:	2877
FOR:	APPARATUS AND METHOD FOR MEASURING THE THICKNESS OF A THIN FILM VIA THE INTENSITY OF REFLECTED LIGHT		

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

AMENDMENT

Applicants are in receipt of the Office Action dated April 23, 2007 of the above-referenced application. Please amend the application as follows:

Amendments to the claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 7 of this paper.